Deformable Mirrors

Lecture 8

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Before we discuss DMs: A digression

Some great images of a curvature AO wavefront sensor from Richard Ordonez, University of Hawaii

Curvature WF Sensor

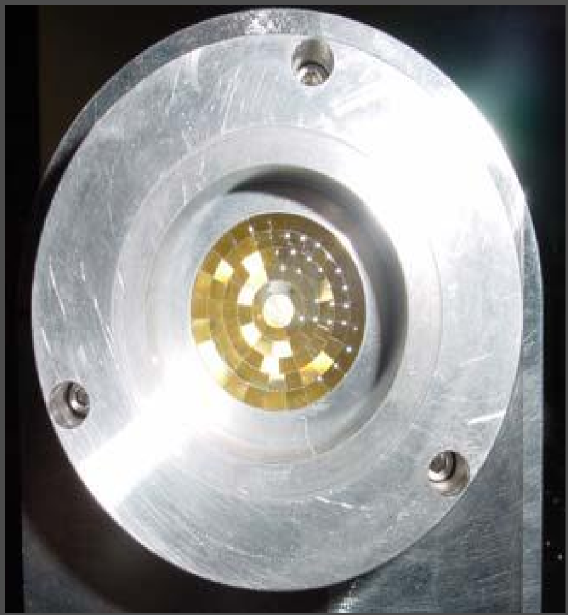
Lenslet Array

Array Mounted in Holder,
Along with Fiber Cables

From presentation by Richard Ordonez, U. of Hawaii Manoa

Curvature WF Sensor

- Collects information about phase curvature and edge-slope data



Lenslet array

Avalanche photodiode array

$$S = \frac{I-E}{I+E}$$

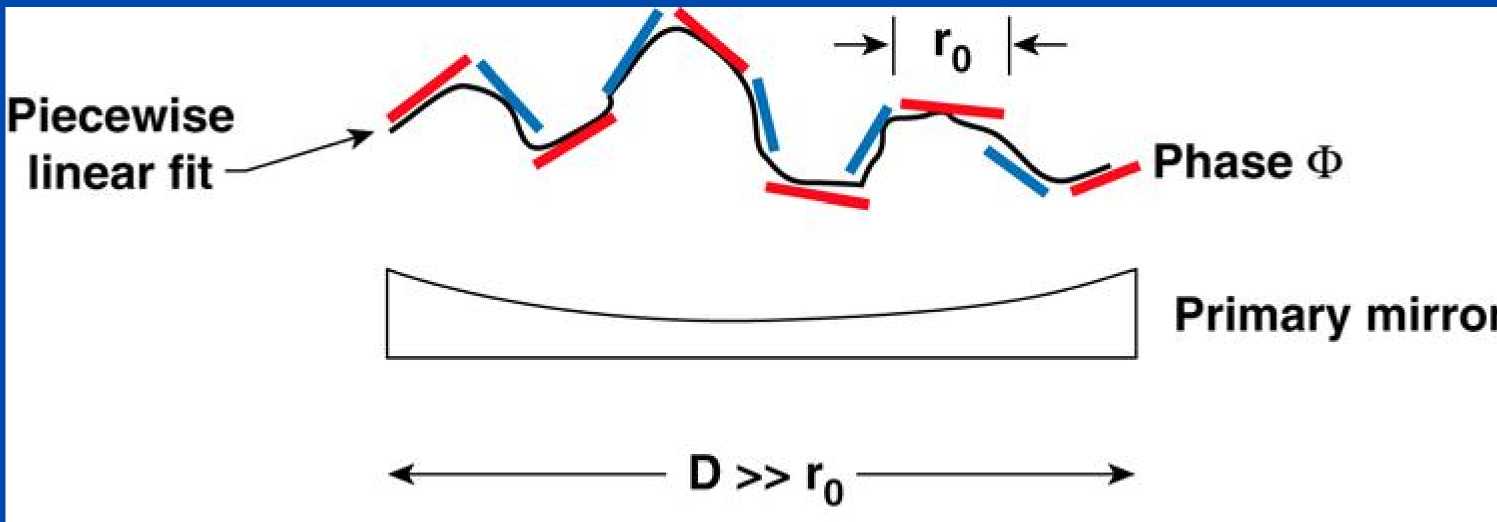
S = *signal*
I = *intra focal images*
E= *Extra focal images*

From presentation by Richard Ordonez, U. of Hawaii Manoa

Outline of Deformable Mirror Lecture

- Performance requirements for wavefront correction
- Types of deformable mirrors
  - Actuator types
  - Segmented DMs
  - Continuous face-sheet DMs
  - Bimorph DMs
  - Adaptive Secondary mirrors
  - MEMS DMs
  - (Liquid crystal devices)
- Summary: fitting error, what does the future hold?

Deformable mirror requirements: r_0 sets number of degrees of freedom of an AO system



- Divide primary mirror into “subapertures” of diameter r_0
- Number of subapertures ~ $(D / r_0)^2$ where r_0 is evaluated at the desired observing wavelength

Overview of wavefront correction

- Divide pupil into regions of ~ size r_0, do "best fit" to wavefront. Diameter of subaperture = d
- Several types of deformable mirror (DM), each has its own characteristic "fitting error"

$$\sigma_{\text{fitting}}^2 = \mu \, (d \, / \, r_0)^{5/3} \ \text{rad}^2$$

- Exactly how large d is relative to r_0 is a design decision; depends on overall error budget

DM requirements (1)

- Dynamic range: stroke (total up and down range)
  - Typical "stroke" for astronomy depends on telescope diameter:
    - ± several microns for 10 m telescope
    - ± 10-15 microns for 30 m telescope
  - Question: Why bigger for larger telescopes?

- Temporal frequency response:
  - DM must respond faster than a fraction of the coherence time τ_0

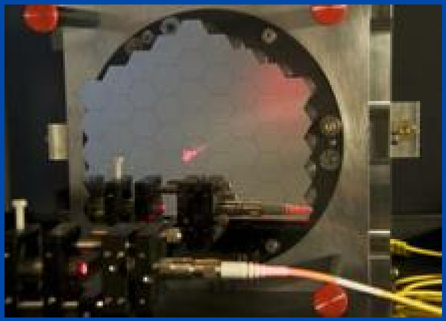
- Influence function of actuators:
  - Shape of mirror surface when you push just one actuator (like a Greens' function)
  - Can optimize your AO system with a particular influence function, but performance is pretty forgiving

DM requirements (2)

- Surface quality:
  - Small-scale bumps can't be corrected by AO
- Hysteresis of actuators:
  - Repeatability
  - Want actuators to go back to same position when you apply the same voltage
- Power dissipation:
  - Don't want too much resistive loss in actuators, because heat is bad ("seeing", distorts mirror)
  - Lower voltage is better (easier to use, less power dissipation)
- DM size:
  - Not so critical for current telescope diameters
  - For 30-m telescope need big DMs: at least 30 cm across
    - Consequence of the Lagrange invariant $y_1\vartheta_1 = y_2\vartheta_2$

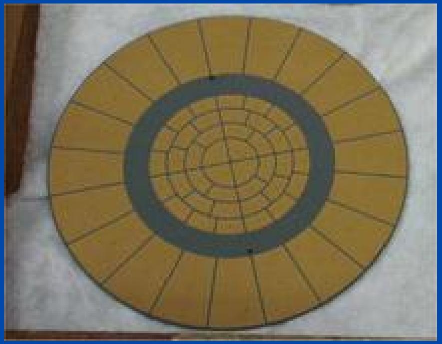
Types of deformable mirrors: conventional (large)

- Segmented
  - Made of separate segments with small gaps



- "Continuous face-sheet"
  - Thin glass sheet with actuators glued to the back

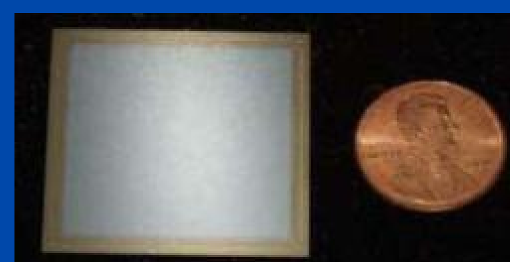
- Bimorph
  - 2 piezoelectric wafers bonded together with array of electrodes between them. Front surface acts as mirror.



Types of deformable mirrors: small and/or unconventional (1)

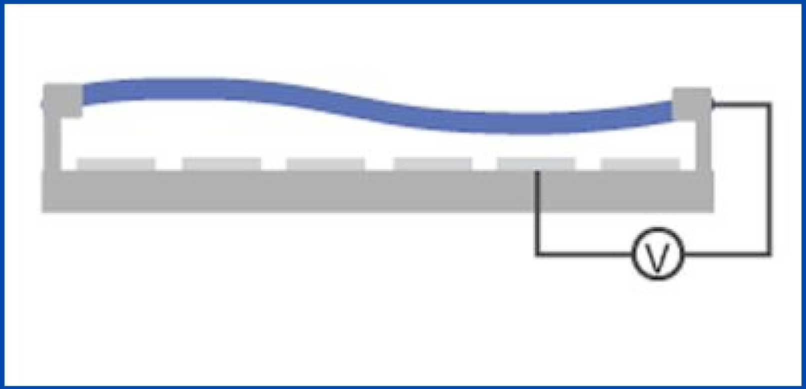
- Liquid crystal spatial light modulators
  - Technology similar to LCDs
  - Applied voltage orients long thin molecules, changes *n*
  - Not practical for astronomy

- MEMS (micro-electro-mechanical systems)
  - Fabricated using micro-fabrication methods of integrated circuit industry
  - Potential to be inexpensive

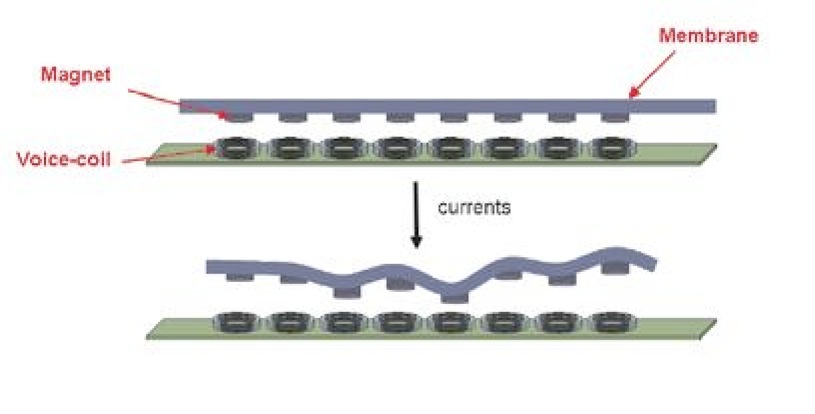


Types of deformable mirrors: small and/or unconventional (2)

- Membrane mirrors
  - Low order correction
  - Example: OKO (Flexible Optical BV)

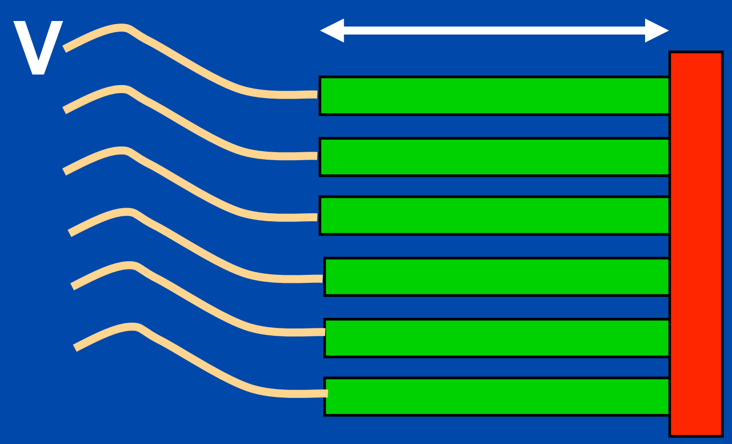


- Magnetically actuated mirrors
  - High stroke, high bandwidth
  - Example: ALPAO



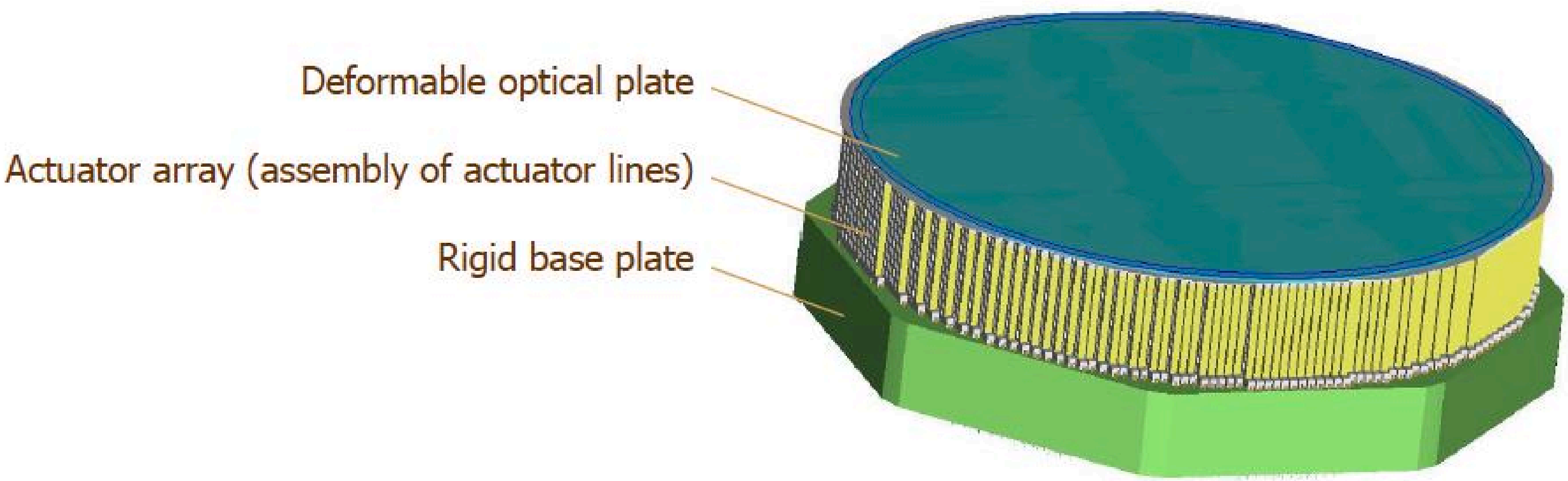
Typical role of actuators in a conventional continuous face-sheet DM

- Actuators are glued to back of thin glass sheet (has a reflective coating on the front)
- When you apply a voltage to the actuator (PZT, PMN), it expands or contracts in length, thereby pushing or pulling on the mirror



Example from CILAS

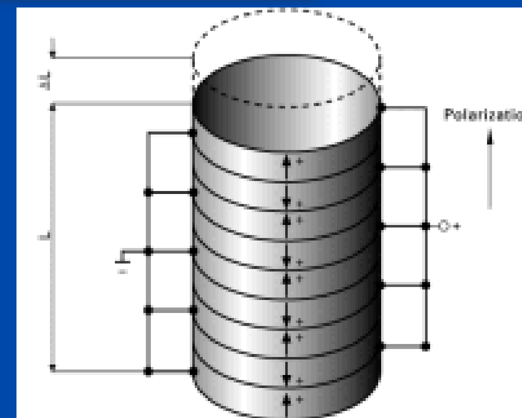
General design of DMs



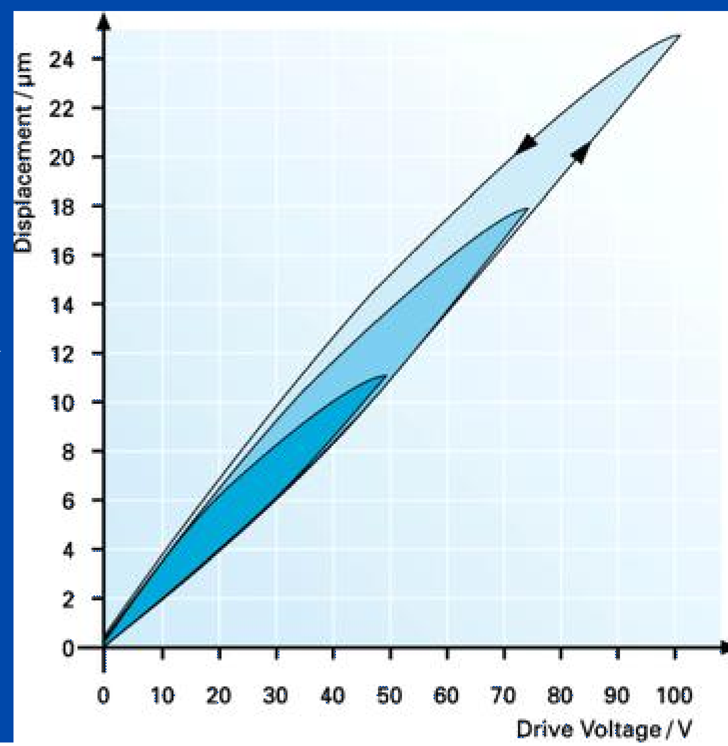
Example (design for TMT): ~ 4500 actuators, 5 mm spacing, Ø ~ 400 mm

Types of actuator: Piezoelectric

- Piezo from Greek for Pressure
- PZT (lead zirconate titanate) gets longer or shorter when you apply V
- Stack of PZT ceramic disks with integral electrodes

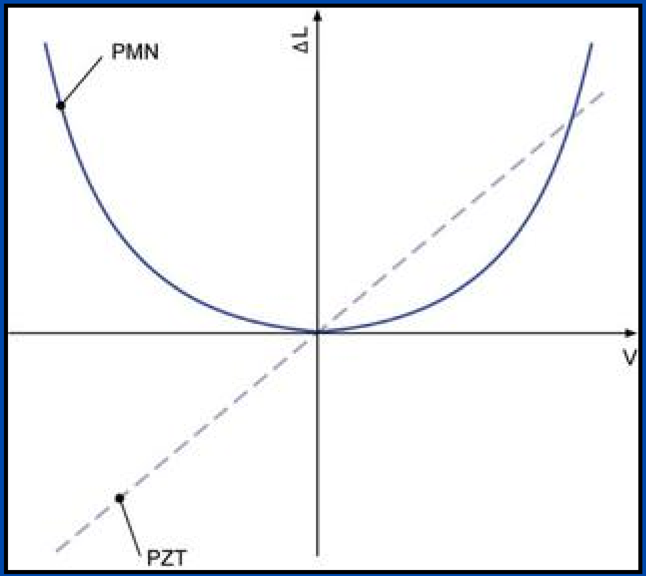


- Displacement linear in voltage
- Typically 150 Volts
  $\Rightarrow \Delta x \sim 10$ microns
- 10-20% hysteresis
  (actuator doesn't go back to exactly where it started)



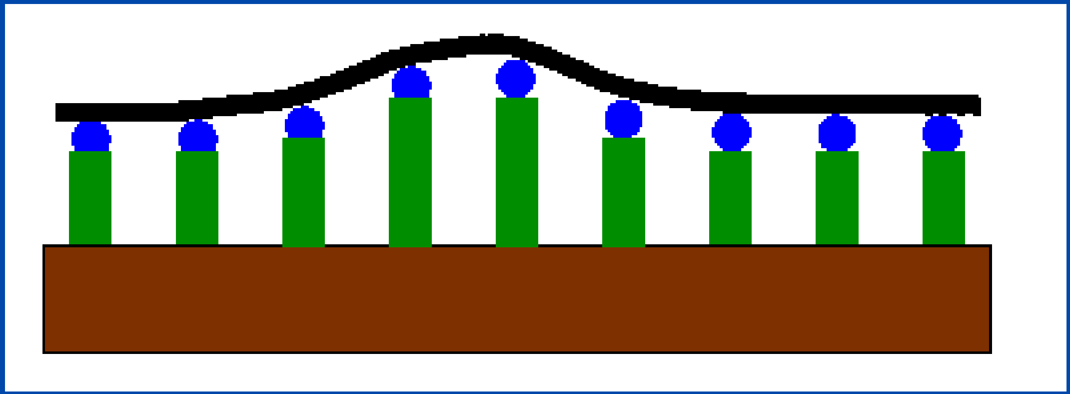
Types of actuator: PMN

- Lead magnesium niobate (PMN)
- Electrostrictive:
  - Material gets longer in response to an applied electric field
- Quadratic response (non-linear)
- Can "push" and "pull" if a bias is applied
- Hysteresis can be lower than PZT in some temperature ranges
- Both displacement and hysteresis depend on temperature (PMN is more temperature sensitive than PZT)



Good reference (figures on these slides): www.physikinstrumente.com/en/products/piezo_tutorial.php

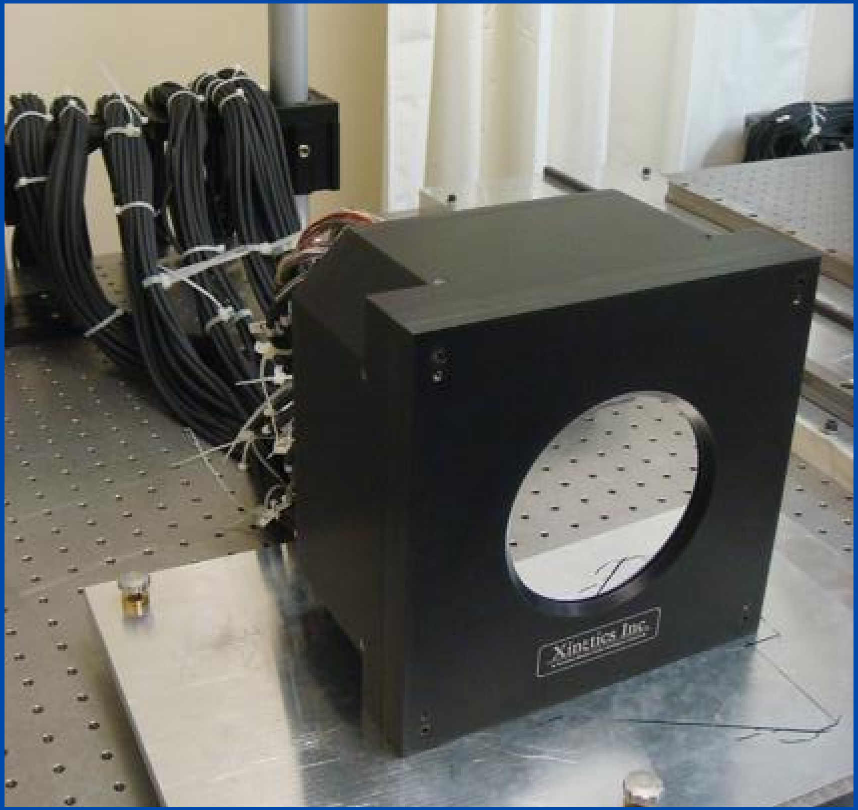
Continuous face-sheet DMs: Design considerations

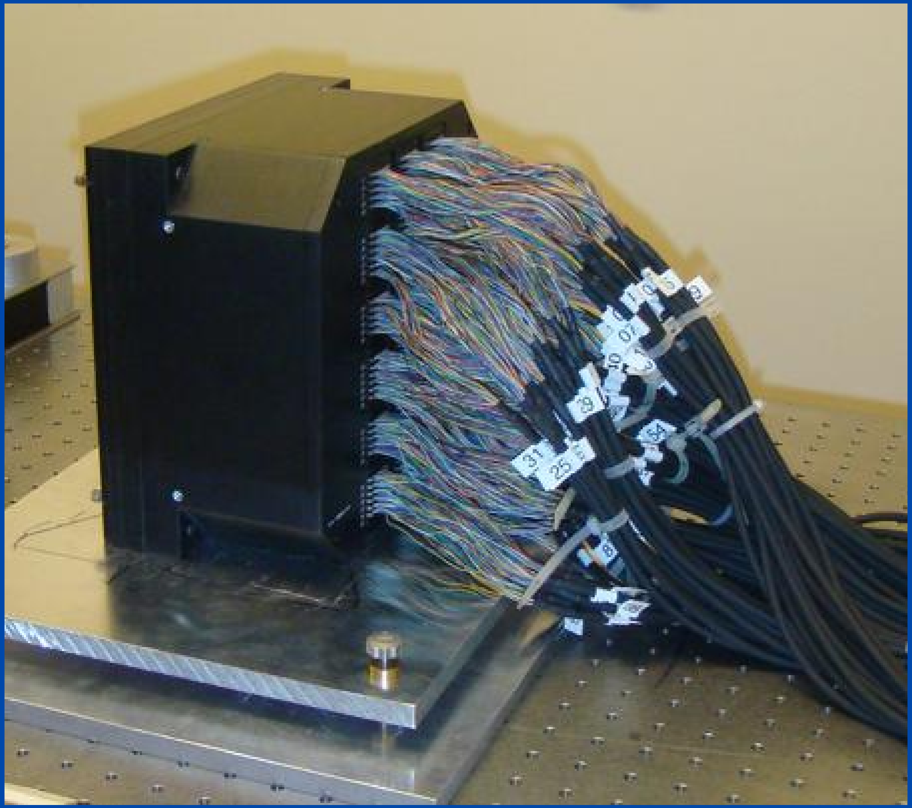


- Facesheet thickness must be large enough to maintain flatness during polishing, but thin enough to deflect when pushed or pulled by actuators
- Thickness also determines "influence function"
  - Response of mirror shape to "push" by 1 actuator
  - Thick face sheets ⇒ broad influence function
  - Thin face sheets ⇒ more peaked influence function
- Actuators have to be stiff, so they won't bend sideways

Palm 3000 High-Order Deformable Mirror: 4356 actuators!

Credit: A. Bouchez

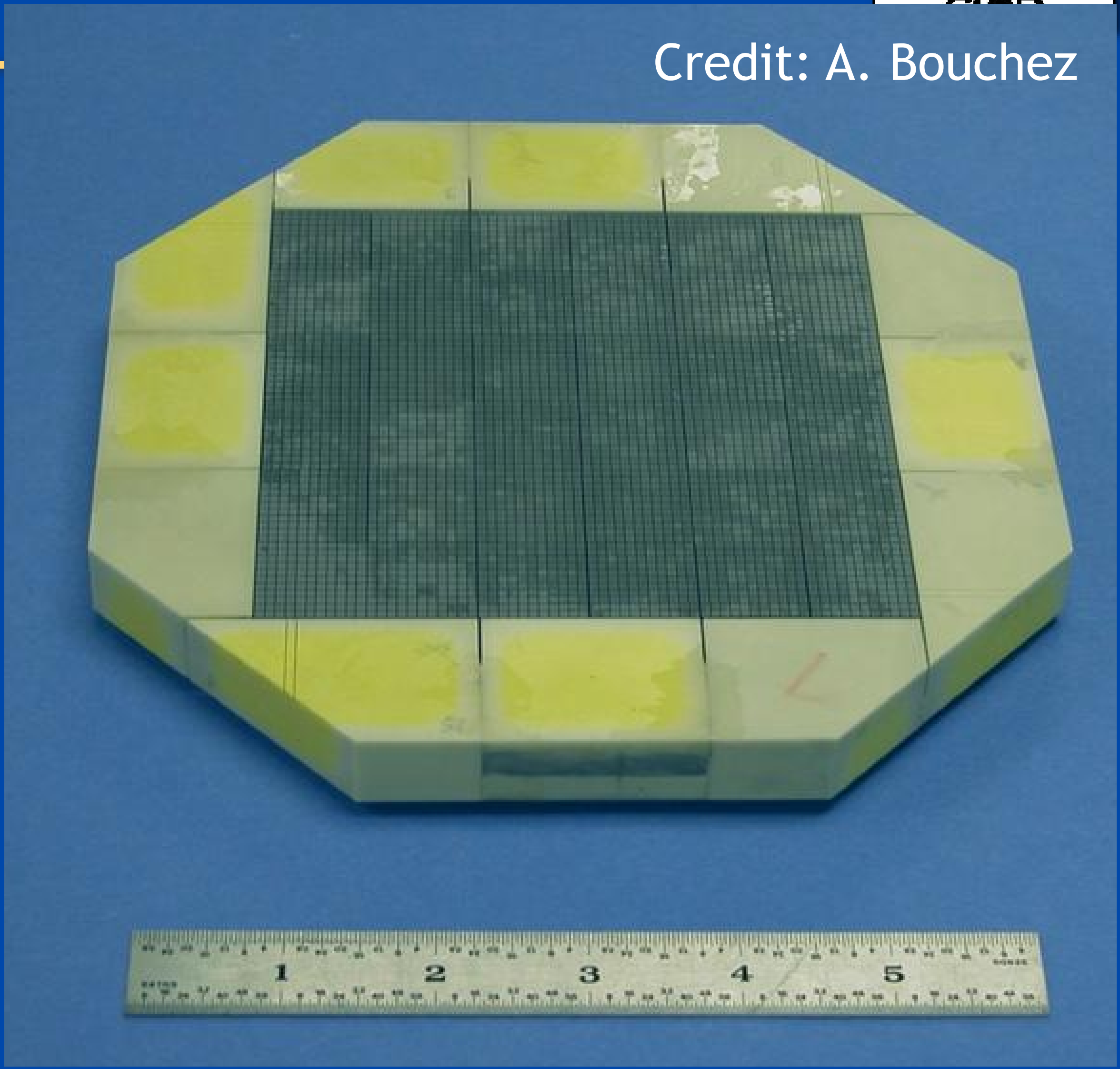




Xinetics Inc. for Mt. Palomar “Palm 3000” AO system

Palm 3000 DM Actuator Structure

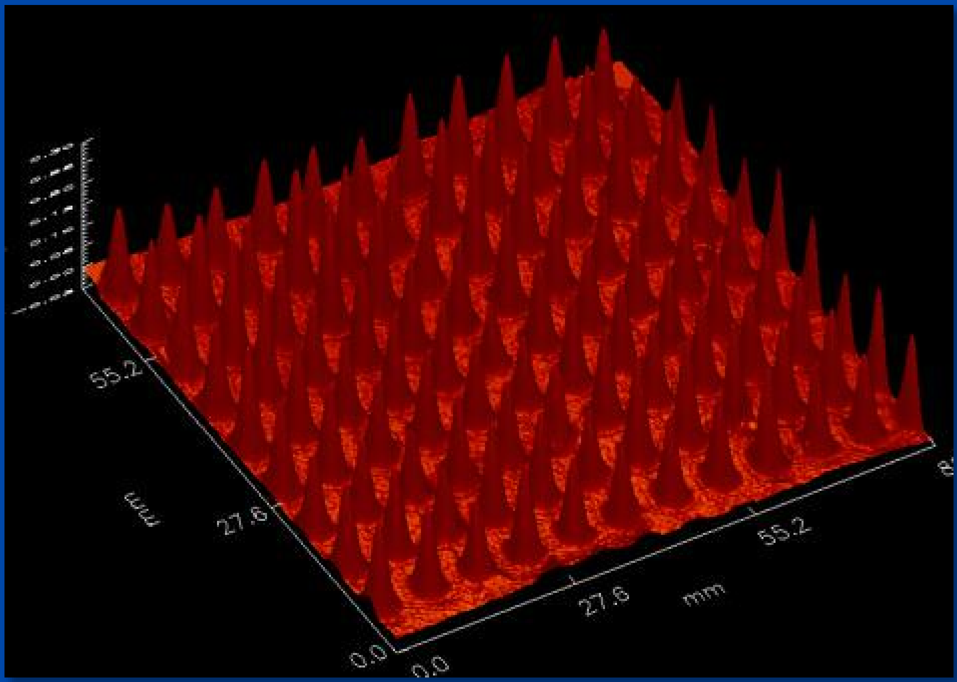
- Actuators machined from monolithic blocks of PMN
- 6x6 mosaic of 11x11 actuator blocks
- 2mm thick Zerodur glass facesheet
- Stroke ~1.4 µm without face sheet, uniform to 9% RMS.



Prior to face sheet bonding

Palm 3000 DM: Influence Functions

Credit: A. Bouchez



- Influence function: response to one actuator
- Zygo interferometer surface map of a portion of the mirror, with every 4th actuator poked

Bimorph mirrors are well matched to curvature sensing AO systems

- Electrode pattern shaped to match sub-apertures in curvature sensor

- Mirror shape W(x,y) obeys Poisson Equation

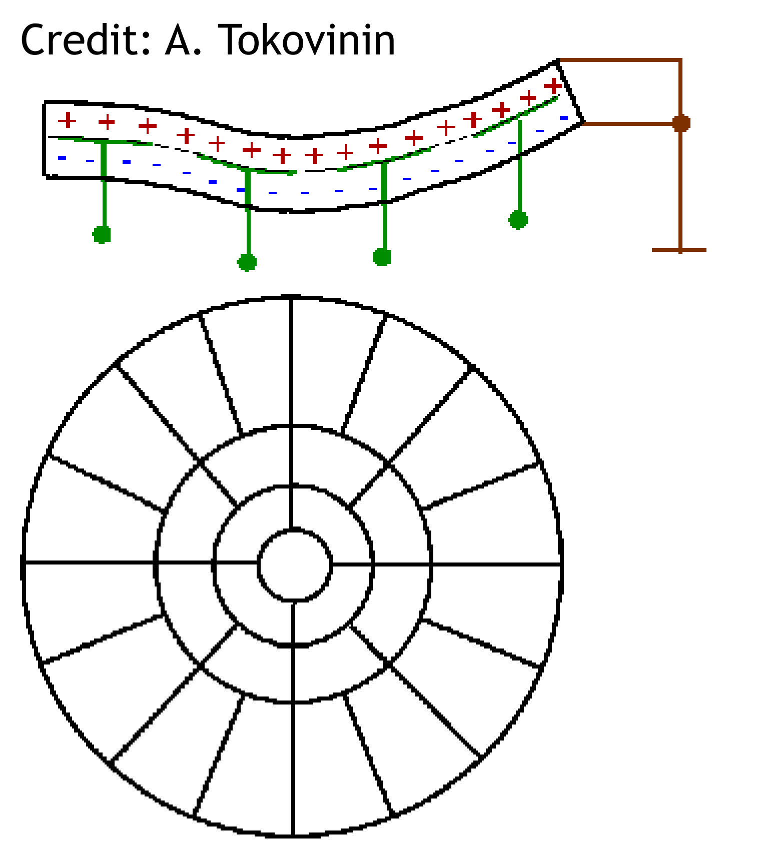
$$\nabla^2\left(\nabla^2 W + AV\right) = 0$$

where $A = 8d_{31} / t^2$

d_{31} is the transverse piezo constant

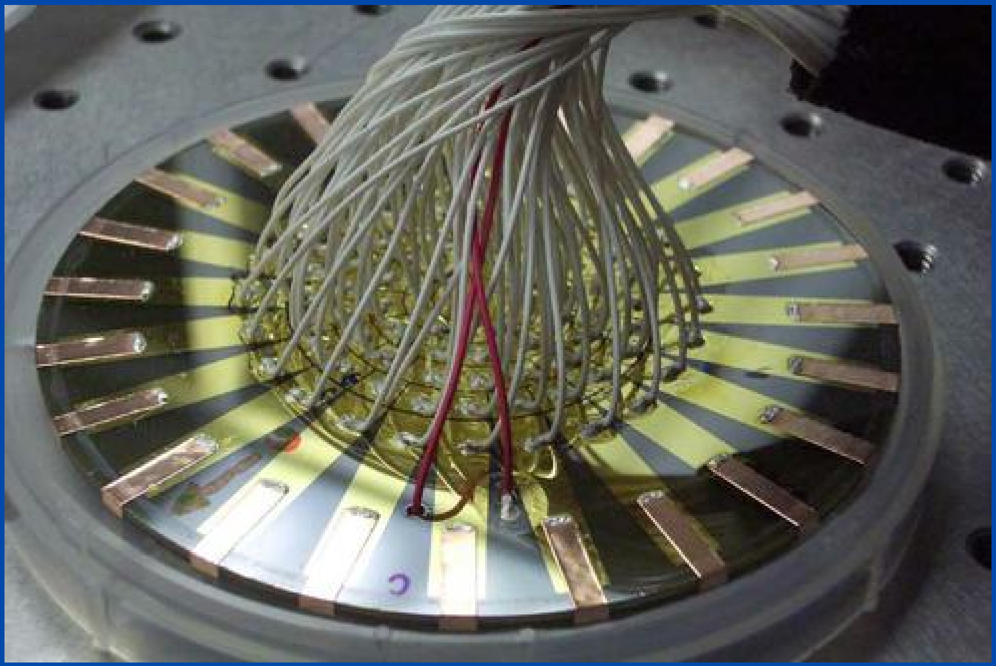
t is the thickness

$V(x,y)$ is the voltage distribution



Bimorph deformable mirrors: embedded electrodes

Electrode Pattern



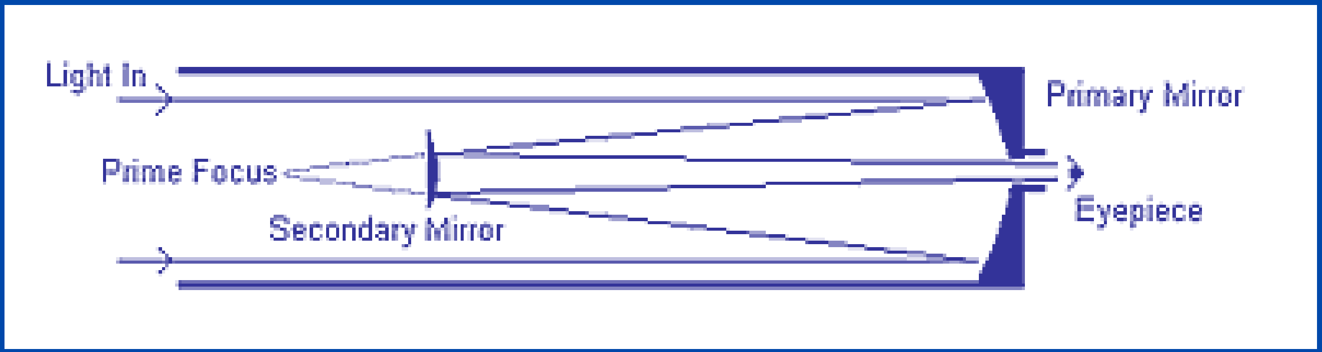
Wiring on back

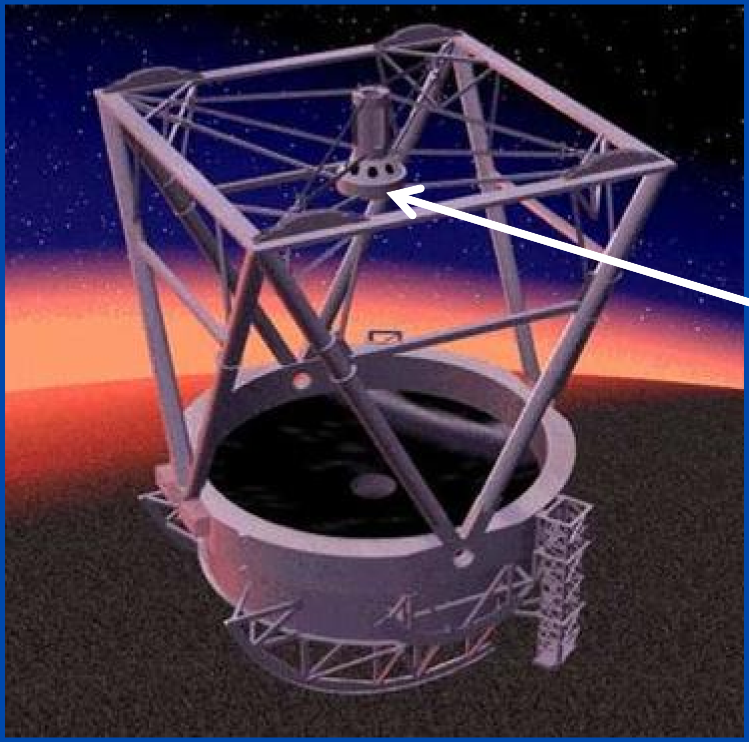
- ESO's Multi Application Curvature Adaptive Optics (MACAO) system uses a 60-element bimorph DM and a 60-element curvature wavefront sensor
- Very successful: used for interferometry of the four 8-m telescopes

Deformable Secondary Mirrors

- Pioneered by U. Arizona and Arcetri Observatory in Italy
- Developed further by Microgate (Italy)
- Installed on:
  - U. Arizona's MMT Upgrade telescope
  - Large binocular telescope (Mt. Graham, AZ)
  - Magellan Clay telescope, Chile
- Future: VLT laser facility (Chile)

Cassegrain telescope concept





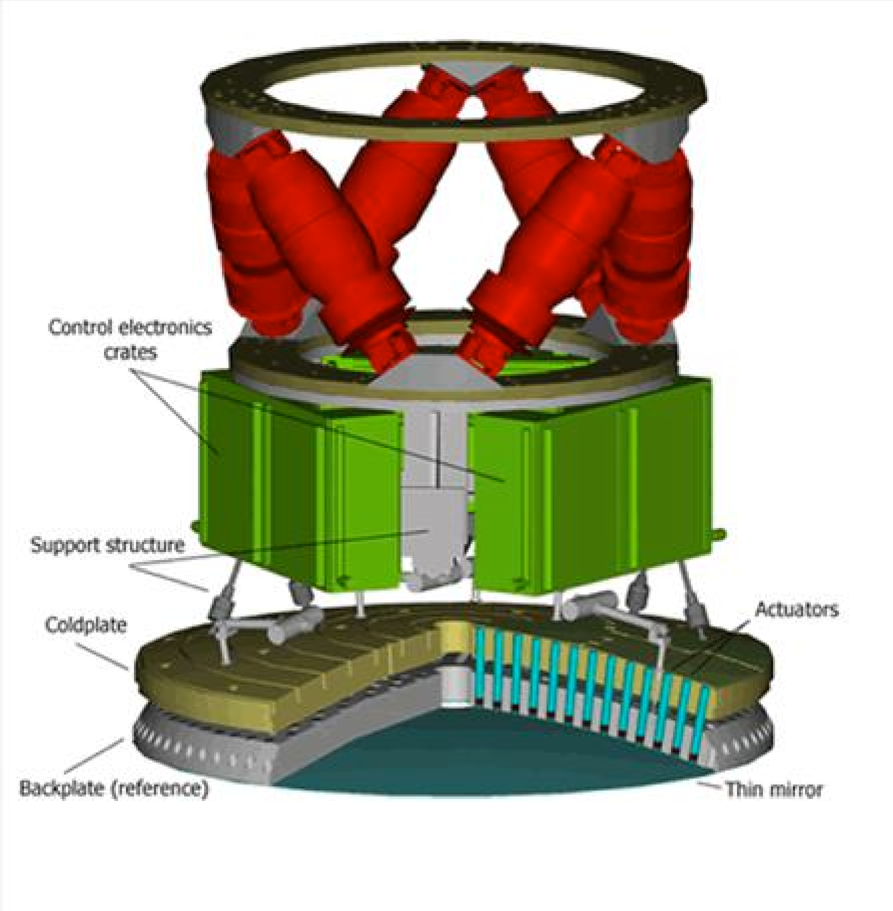
Secondary mirror

Adaptive secondary mirrors

- Make the secondary mirror into the “deformable mirror”
- Curved surface (~ hyperboloid) ⇒tricky
- Advantages:
  - No additional mirror surfaces
    - Lower emissivity. Ideal for thermal infrared.
    - Higher reflectivity. More photons hit science camera.
  - Common to all imaging paths except prime focus
  - High stroke; can do its own tip-tilt
- Disadvantages:
  - Harder to build: heavier, larger actuators, convex.
  - Harder to handle (break more easily)
  - Must control mirror’s edges (no outer “ring” of actuators outside the pupil)

General concept for adaptive secondary mirrors (Arizona, Arcetri, MicroGate)

- Voicecoil actuators are located on rigid backplate or "reference body"
- Thin shell mirror has permanent magnets glued to rear surface; these suspend the shell below the backplate
- Capacitive sensors on backplate give an independent measurement of the shell position



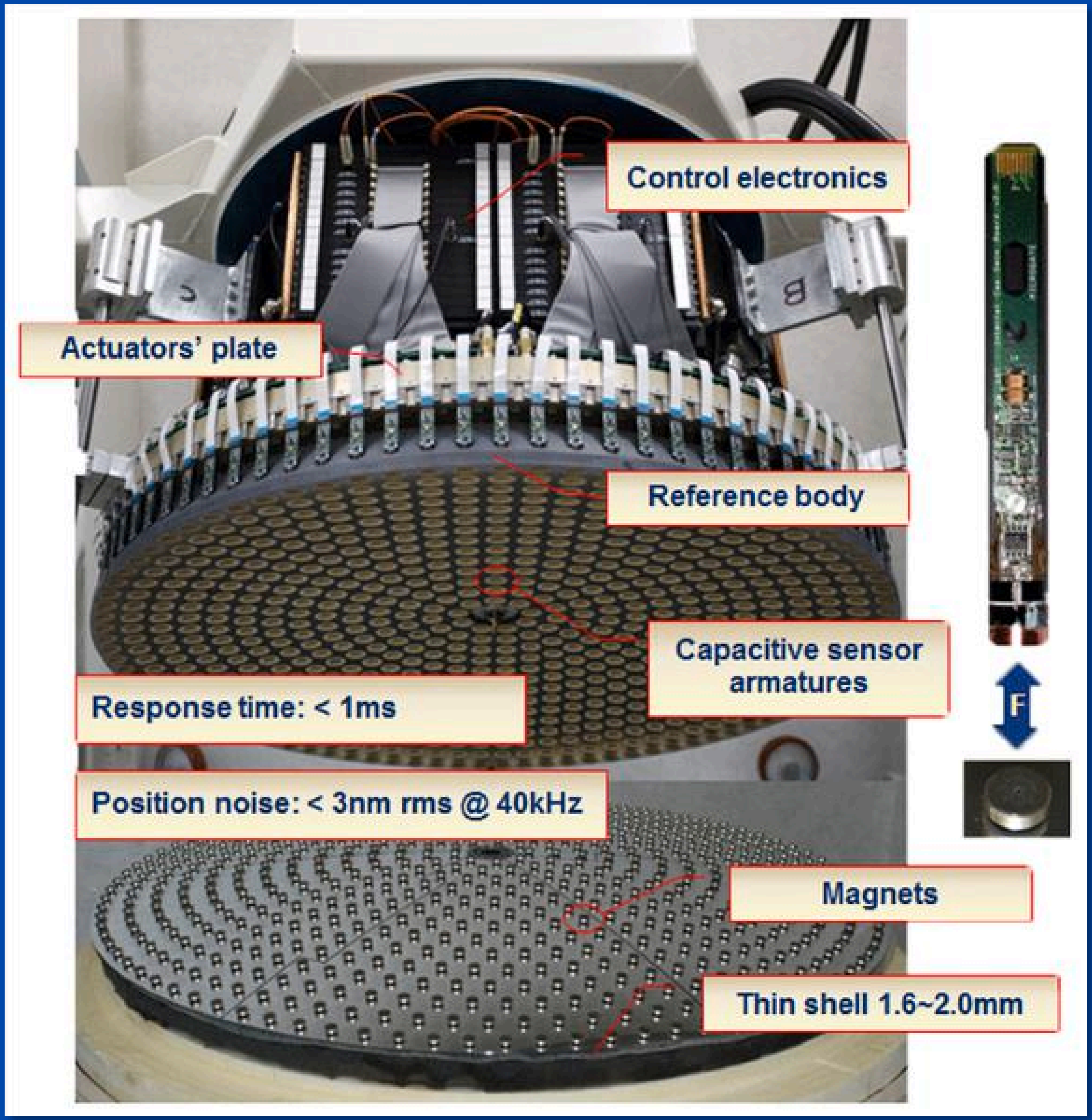


Diagram from MicroGate's website

Shell is VERY thin!

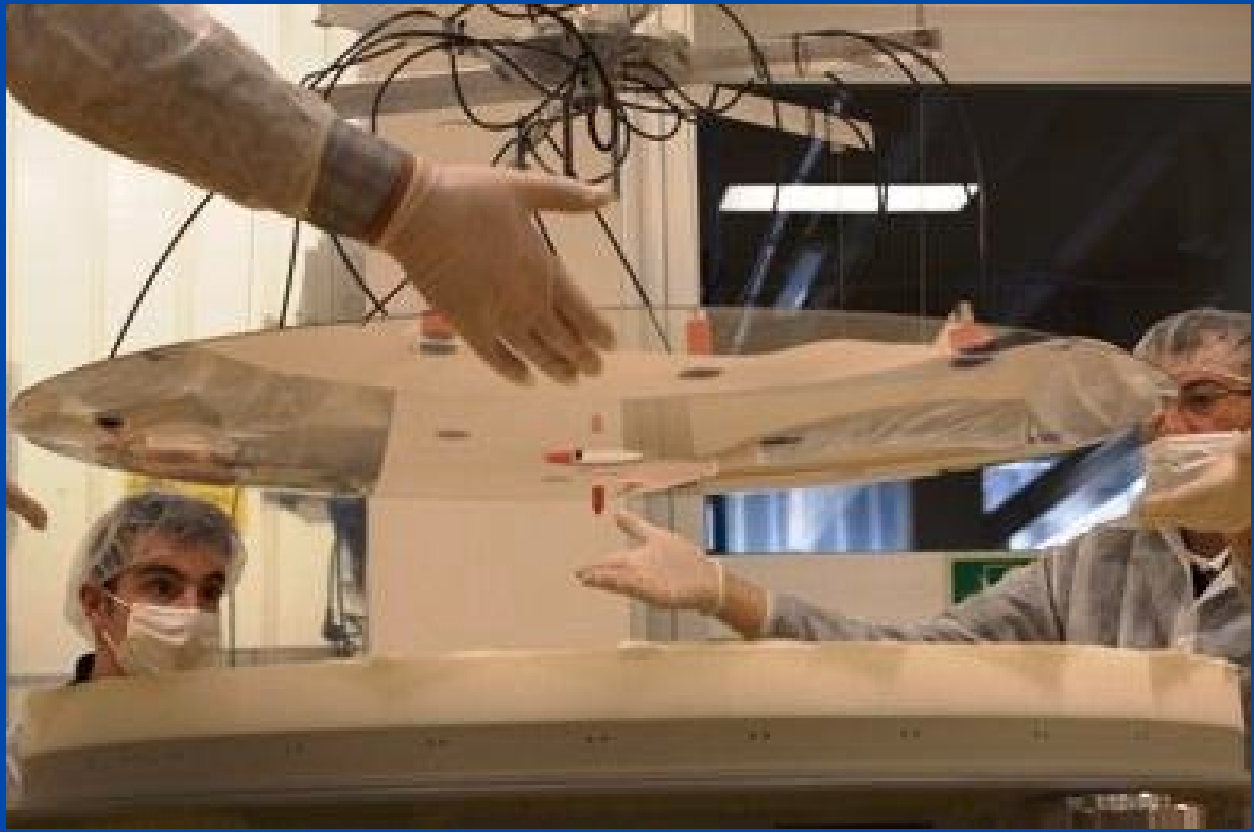
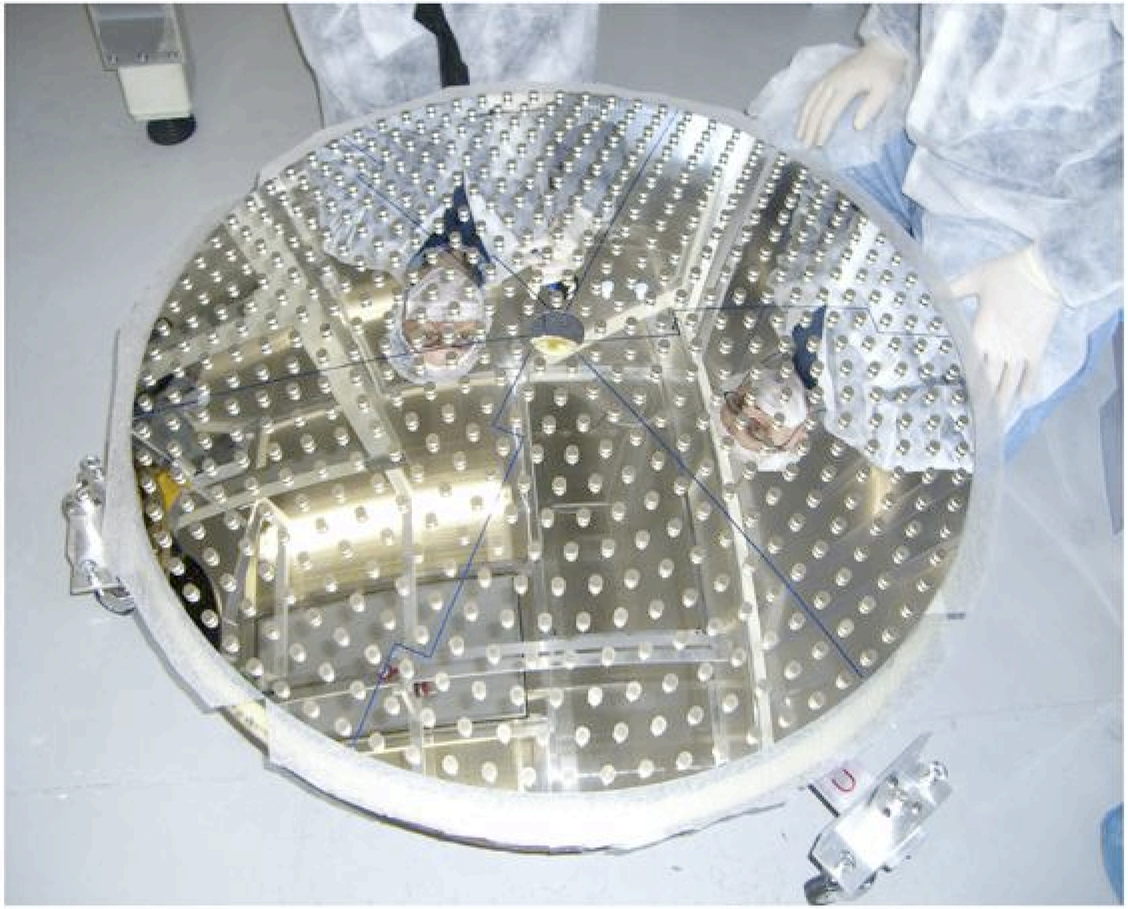


Photo Credit: ADS International

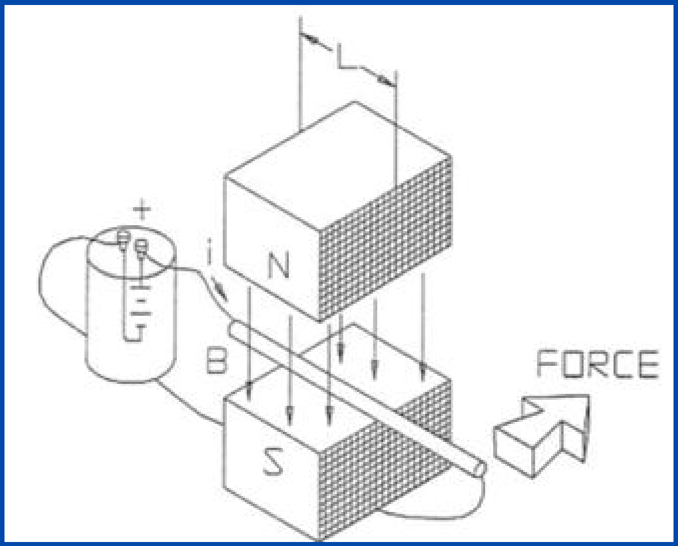
Adaptive secondary mirror for Magellan Telescope in Chile

851mm Magellan ASM shell with Magnets

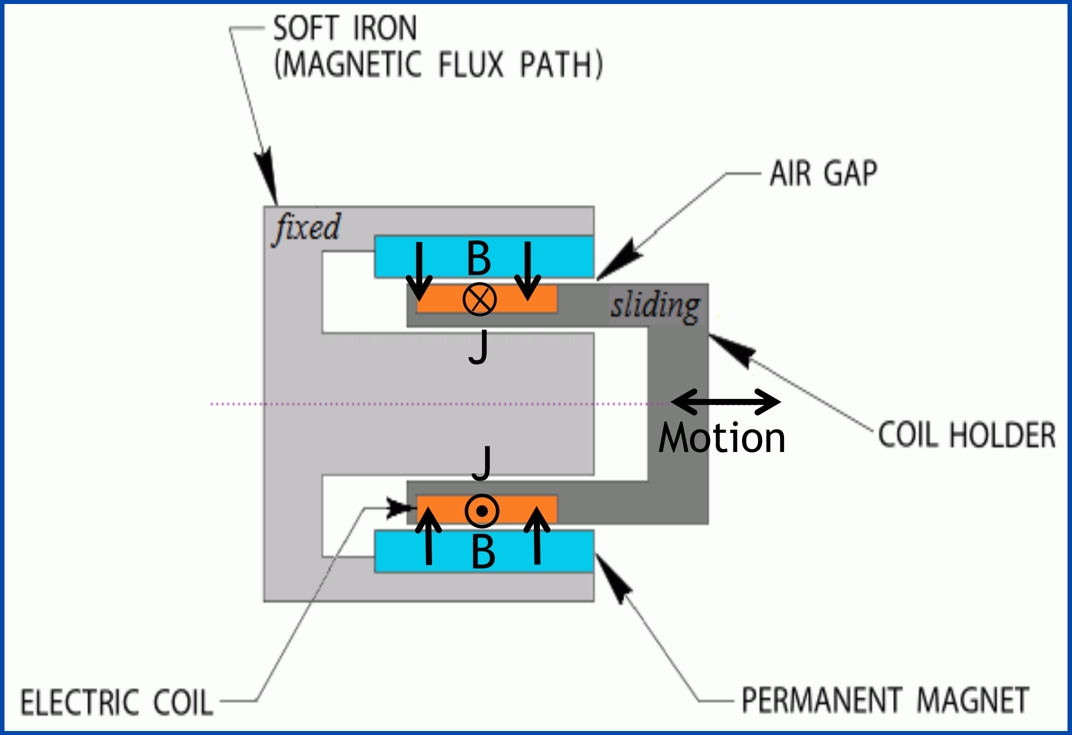


- PI: Laird Close, U. Arizona

Voice coil actuators: large linear range



General principle:
J x B force



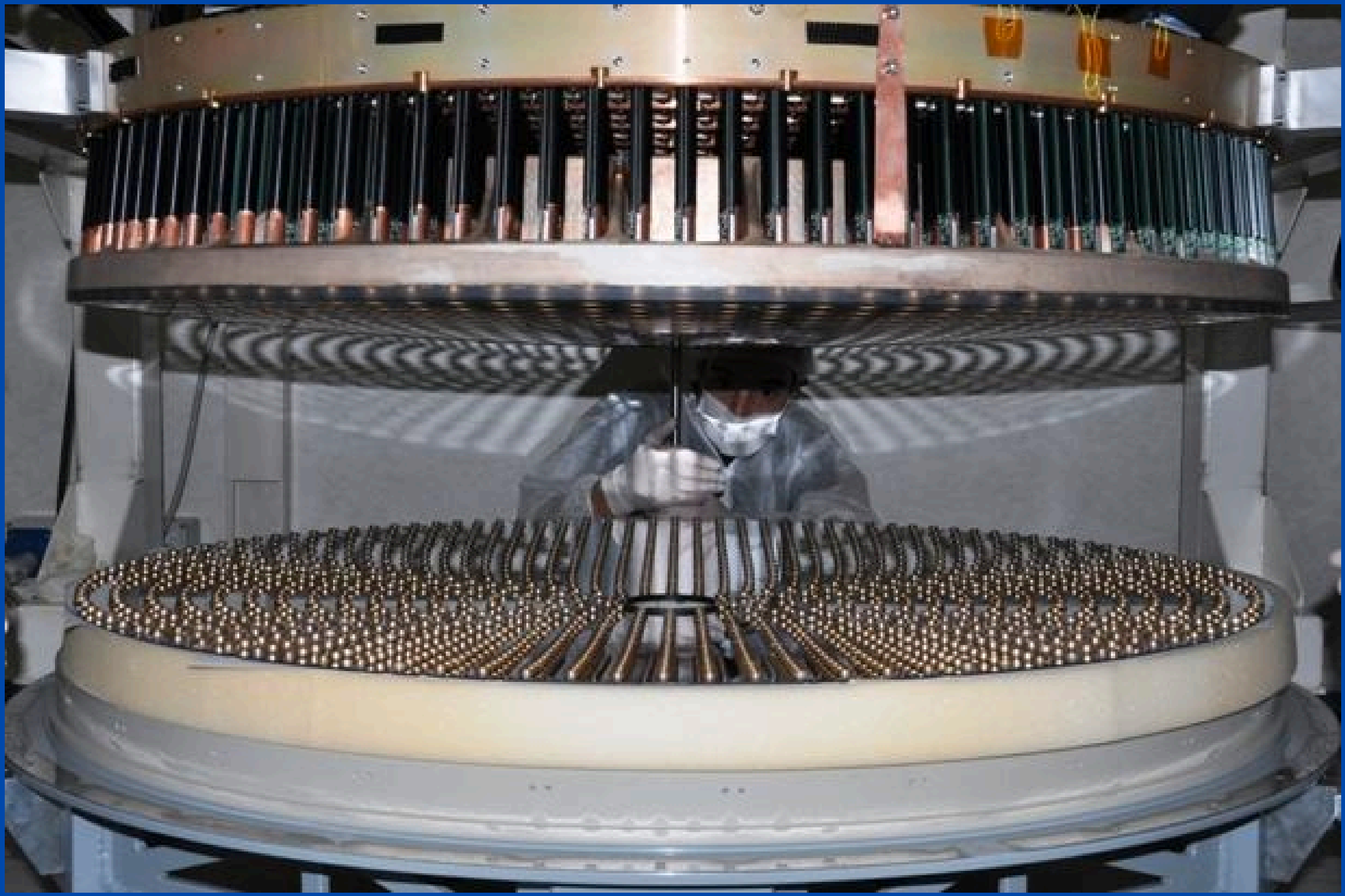
Credit: D. Mawet

Voice coil actuator

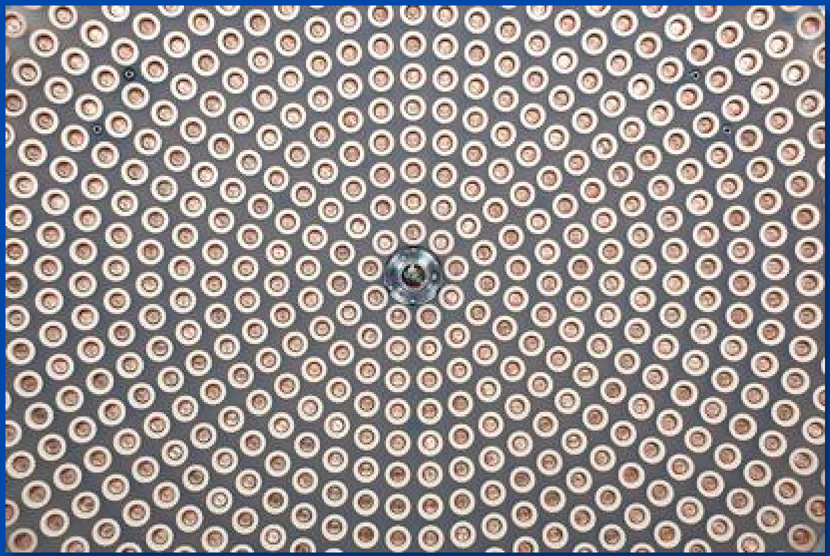
$F = kBLIN$ (Lorentz force)
k = constant
B = magnetic flux density
I = current
N = number of conductors

(c) Micro gate

Voice-Coil Actuators viewed from the side



Deformable secondaries: embedded permanent magnets

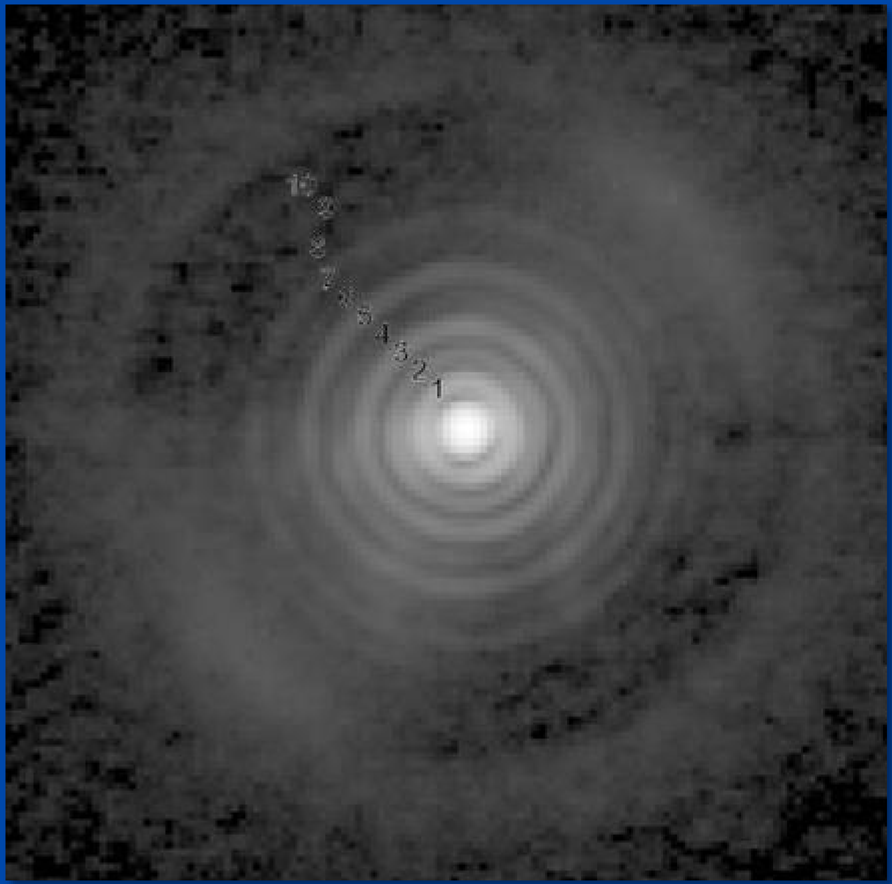


LBT DM: magnet array

LBT DM: magnet close-up

Adaptive secondary DMs have inherently high stroke: no need for separate tip-tilt mirror!

It Works! 10 Airy rings on the LBT!



- Strehl ratio > 80%

Concept Question

- Assume that its adaptive secondary mirror gives the 6.5 meter MMT telescope's AO system twice the throughput (optical efficiency) as conventional AO systems.
  - Imagine a different telescope (diameter D) with a conventional AO system.
  - For what value of D would this telescope+AO system have the same light-gathering power as the MMT?

Cost scaling will be important for future giant telescopes

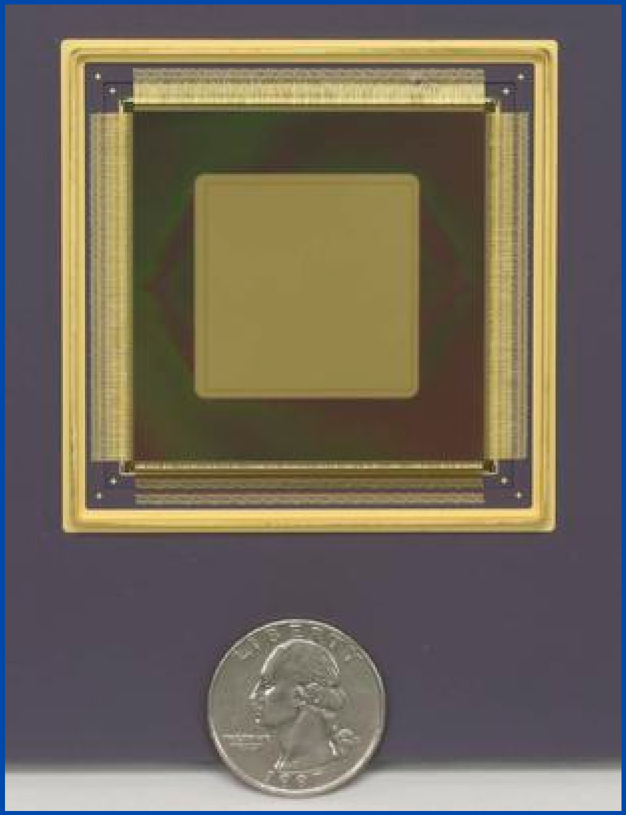
- Conventional DMs
  - About $1000 per degree of freedom
  - So $1M for 1000 actuators
  - Adaptive secondaries cost even more.
    - » VLT adaptive secondaries in range $12-14M each

- MEMS (infrastructure of integrated circuit world)
  - Less costly, especially in quantity
  - Currently ~ $100 per degree of freedom
  - So $100,000 for 1000 actuators
  - Potential to cost 10's of $ per degree of freedom

What are MEMs deformable mirrors?

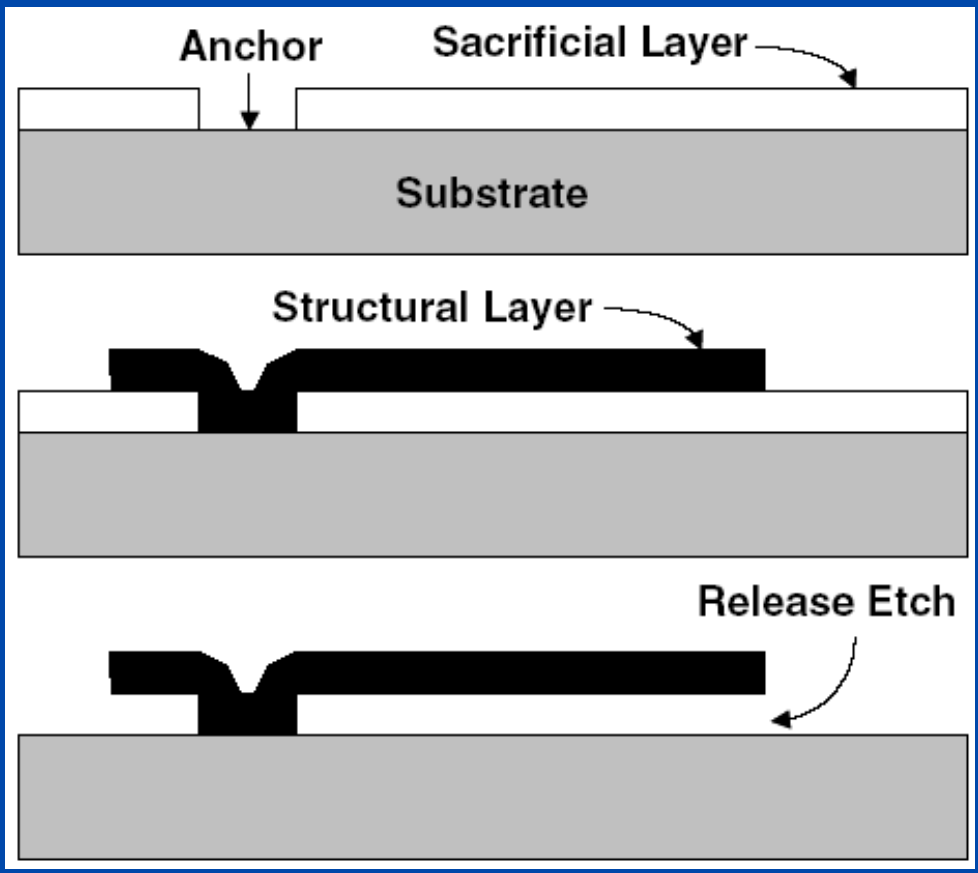
MEMS: Micro-electro-mechanical systems

- A promising new class of deformable mirrors, MEMs DMs, has recently emerged
- Devices fabricated using semiconductor batch processing technology and low power electrostatic actuation
- Potential to be less expensive ($10 - $100/actuator instead of $1000/actuator)



4096-actuator MEMS deformable mirror. Photo courtesy of Steven Cornelissen, Boston Micromachines

One MEMS fabrication process: surface micromachining



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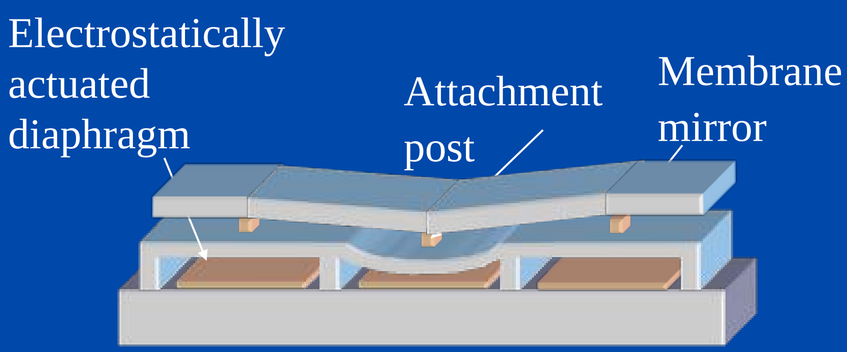
Boston University MEMS Concept



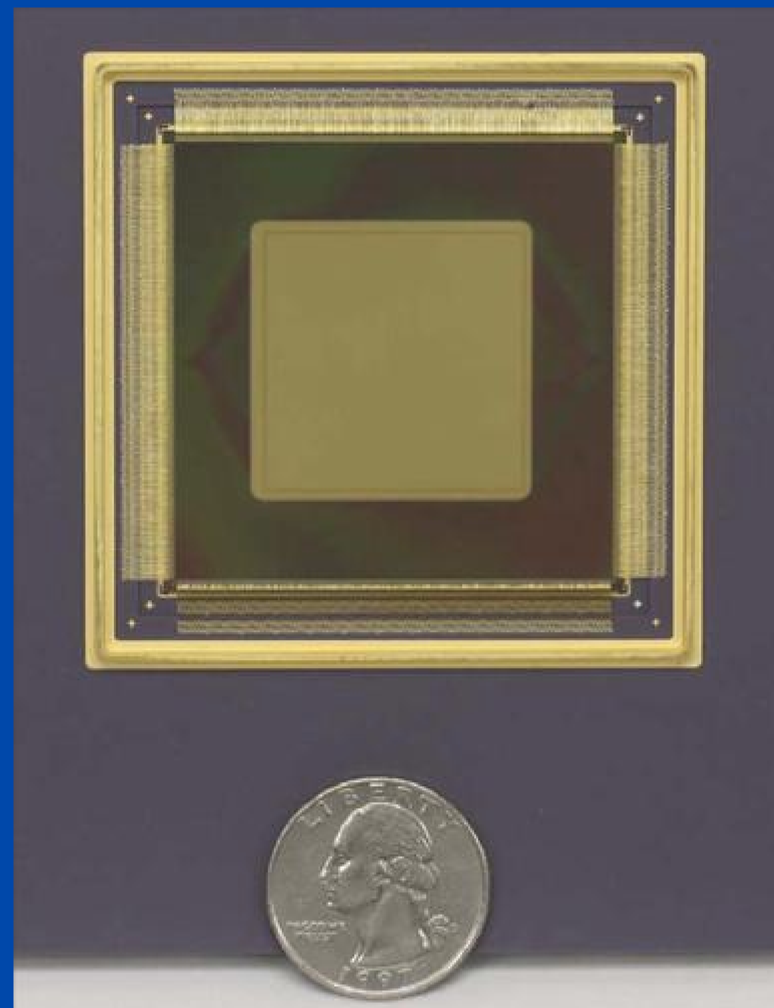
Continuous mirror

- Fabrication: Silicon micromachining (structural silicon and sacrificial oxide)
- Actuation: Electrostatic parallel plates

Boston University
Boston MicroMachines

Boston Micromachines: 4096 actuator MEMS DM

- Mirror for Gemini Planet Imager
- 4096 actuators
- 64 x 64 grid
- About 2 microns of stroke



MEMS testing: WFE < 1 nm rms in controlled range of spatial frequencies

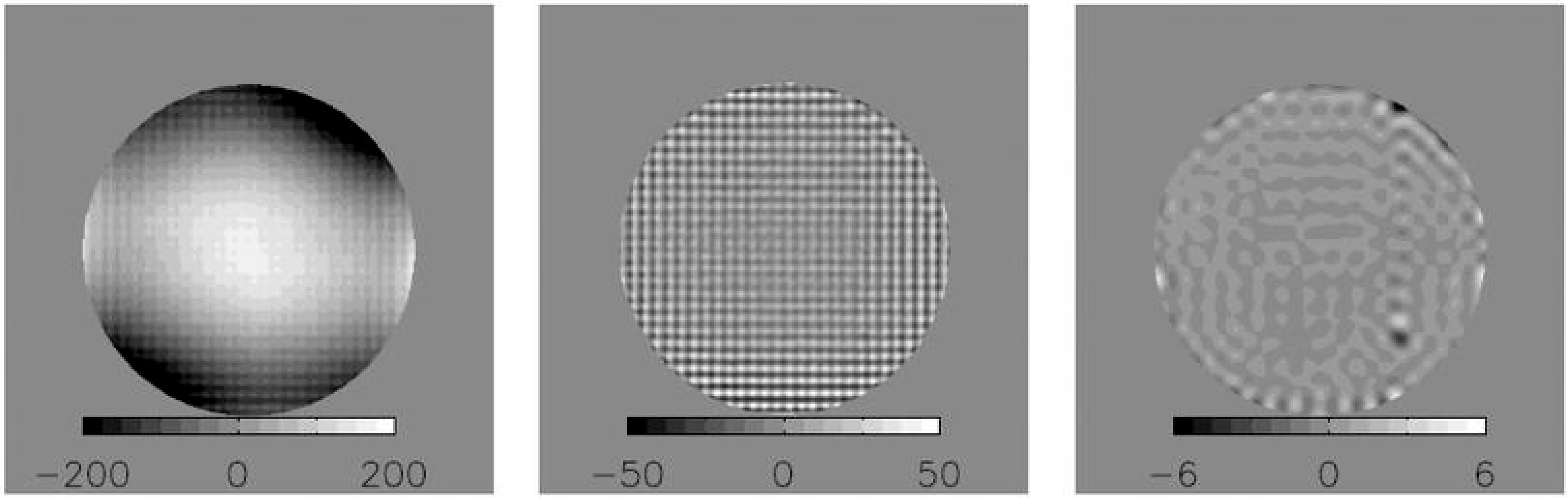
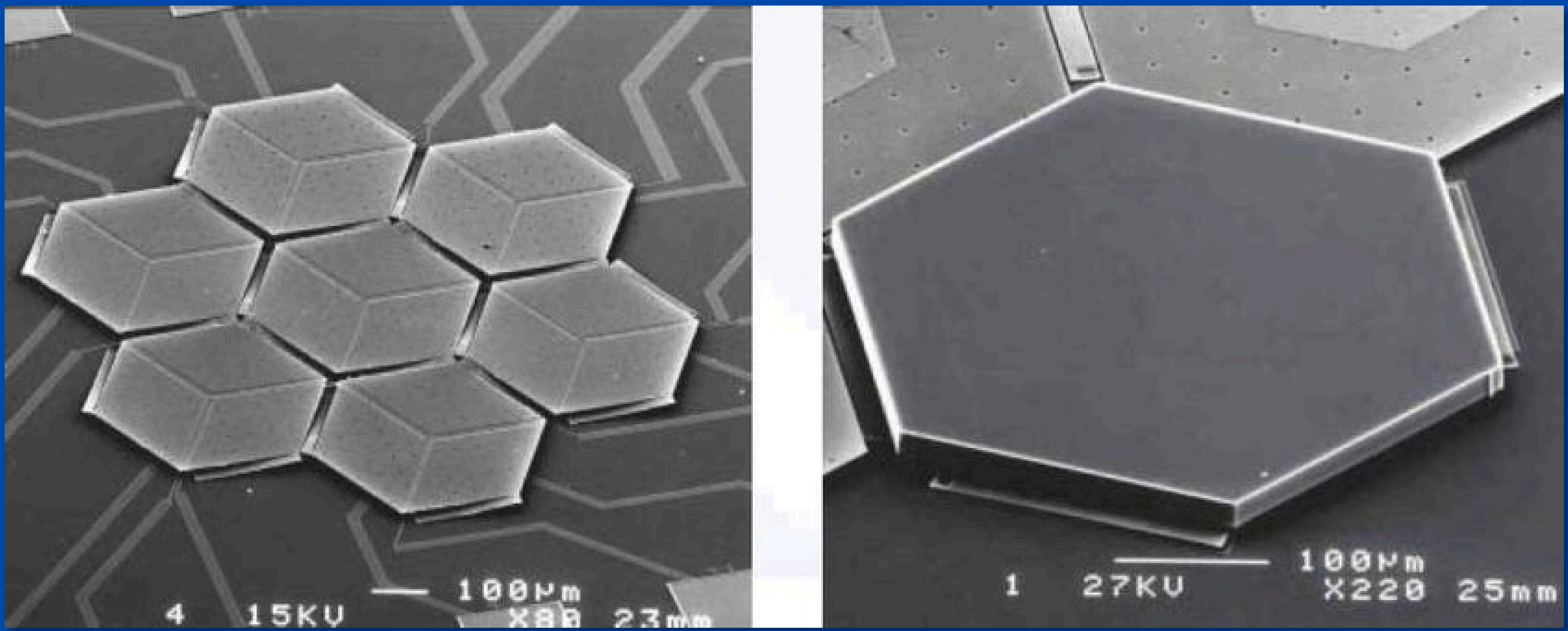


Figure 2. Wavefronts taken before and after a closed loop test with a 9.2 mm aperture. The initial wavefront has an RMS wavefront error of 148 nm (left), while the flattened wavefront has 12.8 nm total RMS wavefront error (center), which is mostly errors on the scale on an individual actuator. Inside the controlled range of spatial frequencies the RMS wavefront error is 0.54 nm. This is seen more clearly in the low-pass filtered image (right).

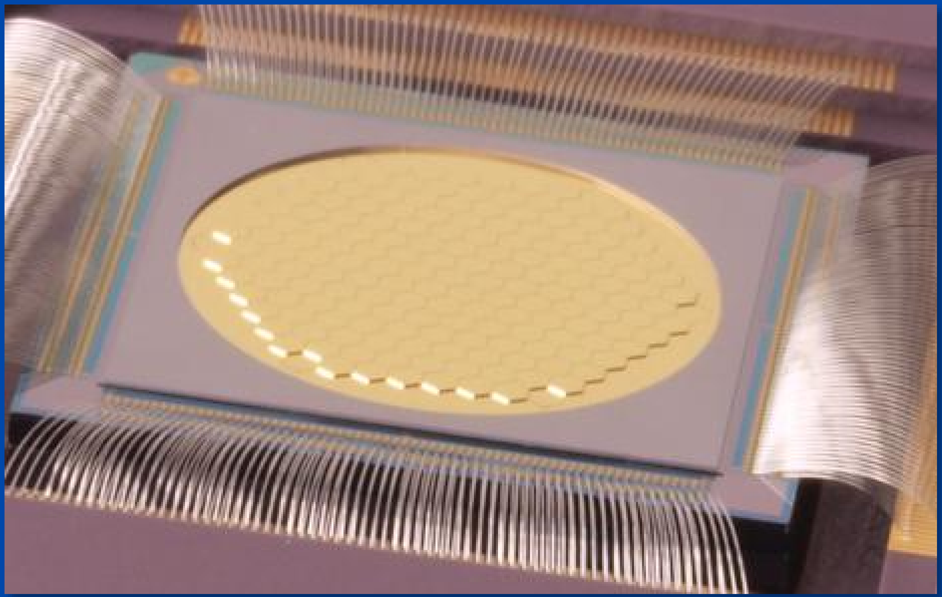
Credit: Morzinski, Severson, Gavel, Macintosh, Dillon (UCSC)

Another MEMS concept: IrisAO's segmented DM



- Each segment has 3 degrees of freedom
- Now available with 100's of segments
- Large stroke: > 7 microns

- IrisAO PT489 DM
- 163 segments, each with 3 actuators (piston +tip+tilt)
- Hexagonal segments, each made of single crystal silicon
- 8 microns of stroke (large!)



Issues for all MEMS DM devices

- "Snap-down"
  - If displacement is too large, top sticks to bottom and mirror is broken (can't recover)
- Robustness not well tested on telescopes yet
  - Sensitive to humidity (seal using windows)
  - Will there be internal failure modes?
- Defect-free fabrication
  - Current 4000-actuator device still has quite a few defects

Concept Question

- How does the physical size (i.e. outer diameter) of a deformable mirror enter the design of an AO system?
  - Assume all other parameters are equal: same number of actuators, etc.

Fitting errors for various DM designs

$$\sigma_{fitting}^2 = \mu \, (d / r_0)^{5/3} \text{ rad}^2$$

DM Design	μ	Actuators / segment
Piston only, square segments	1.26	1
Piston+tilt, Square segments	0.18	3
Continuous DM	0.28	1

Consequences: different types of DMs need different actuator counts, for same conditions

- To equalize fitting error for different types of DM, number of actuators must be in ratio

$$\left(\frac{N_1}{N_2}\right) = \left(\frac{d_2}{d_1}\right)^2 = \left(\frac{a_{F_1}}{a_{F_2}}\right)^{6/5}$$

- So a piston-only segmented DM needs (1.26 / 0.28)$^{6/5}$ = 6.2 times more actuators than a continuous face-sheet DM!

- Segmented mirror with piston <u>and</u> tilt requires 1.8 times more actuators than continuous face-sheet mirror to achieve same fitting error: $N_1 = 3N_2\,(0.18 / 0.28)^{6/5} = 1.8\,N_2$

Summary of main points

- Deformable mirror acts as a "high-pass filter"
  - Can't correct shortest-wavelength perturbations
- Different types of mirror have larger/smaller fitting error
- Large DMs have been demonstrated (continuous face sheet, adaptive secondary) for ~ 1000 - 3000 actuators
- MEMs DMs hold promise of lower cost, more actuators
- Deformable secondary DMs look very promising
  - No additional relays needed (no off-axis parabolas), fewer optical surfaces
  - Higher throughput, lower emissivity
  - Early versions had problems; VLT has re-engineered now